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Statement By Applicant

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10/803,453

Applicants:

George, et al

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2821

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Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
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	2	4,252,608	2/24/1981	Baldwin et al			
	3	4,358,686	11/9/1982	Kinoshita			
	4	4,362,632	12/7/1982	Jacob			
	5	4,431,898	2/14/1984	Reinberg et al			
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	9	4,918,031	4/17/1990	Flamm et al			
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	15	5,198,634	3/30/1993	Mattson et al			
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	4	Letts, S. L. et al., "Laser Program Annual Report-1978," vol. 1, Lawrence Livermore Report UCRL-50021-78, pp. 4-7 to 4-11.
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	6	B1-B5 Photocopies of sections of Lawrence Livermore Laboratory Drawing No. AAA-78-107861-00, June 1978, drawn by R. Dowrick.
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	8	Flamm, Letter from D. L. Flamm to B. S. Schneider dated Jul. 8, 1989.
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	10	Flamm, Letter from D. L. Flamm to A. Manza dated Jun. 18, 1990.
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	13	Eckert, "The Hundred Year History Of Induction Discharges", 1986, Proceedings 2nd Annual International Conference on Plasma Chemistry and Technology, Herman Boenig, Ed., Techromic Publ., Lancaster, PA, pp 171-202.
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	16	Probyn, "Sputtering of Insulators in an RF Discharge", 1968, Vacuum, vol. 18, No. 5, pp. 253-257.
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Examiner		Date Considered
AC		4/10/07

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



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Information Disclosure Statement By Applicant
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	D						
	E						
	F						
	G						

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
	H						Yes	No
	I							
	J							
	K							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	L	
	M	
	N	
Examiner	Date Considered	
	4/10/07	

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Form 2449 (Modified)

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U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A						
	B						
	C						
	D						
	E						
	F						
	G						

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	H							
	I							
	J							
	K							

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Examiner		Date Considered
AC		4/10/02

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.